

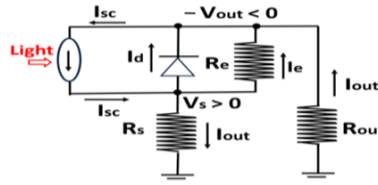
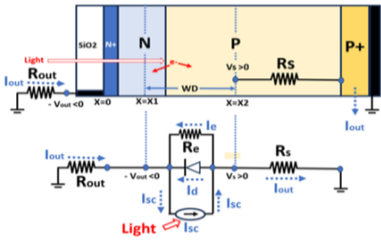
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Impurity Atom Density	Resistivity N type Wafer	Resistivity P type Wafer	Substrate Resistance (Rs) 1 cm ² P type Wafer
10^{16} cm^{-3}	~0.5 Ωcm	~ 1 Ωcm	~ 0.02 Ωcm
10^{15} cm^{-3}	~ 5 Ωcm	~ 10 Ωcm	~ 0.2 Ωcm
10^{14} cm^{-3}	~50 Ωcm	~ 200 Ωcm	~ 4 Ωcm

$$R_s = (L)(\rho)/(A)$$

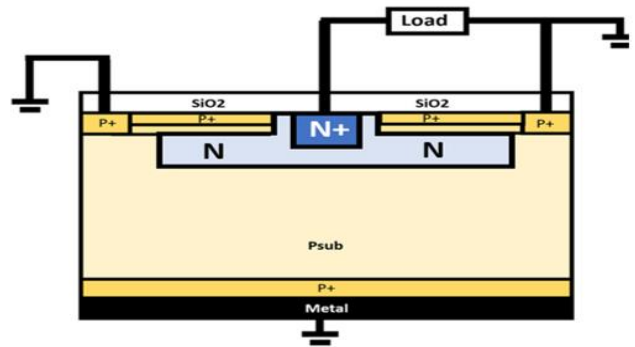
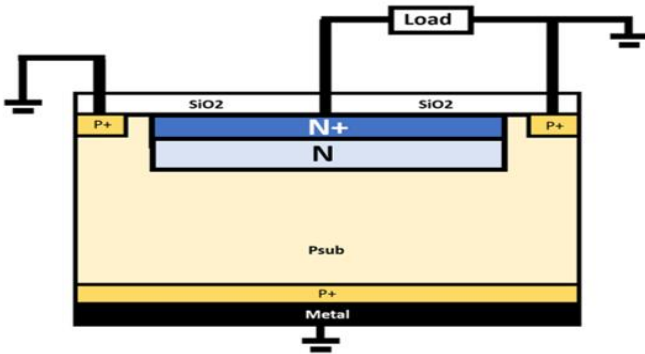
For P-type 1 cm x 1 cm silicon chip with a thickness of 200 μm,

$$R_s \sim (200 \mu\text{m})(200\Omega\text{cm})/(10^8 \mu\text{m}^2) \sim 4\Omega ;$$



(A) Conventional Low-cost Four-Mask N+NPP+ Single Junction Solar Cell without high-energy ion-implantation

(B) P+ Pinned-Surface Six-Mask P+PNPP+ Double Junction Solar Cell with high-energy ion-implantation for Buried N Channel formation



- (Mask01) P+ Channel Stop
- (Mask02) N+N Charge Outlet
- (Mask03) Metal Contact
- (Mask04) Metal Wire

- (Mask01) P+ Channel Stop
- (Mask02) N+ Charge Outlet
- (Mask03) Buried N Channel
- (Mask04) Pinned-Surface P+ region
- (Mask05) Metal Contact
- (Mask06) Metal Wire

